

Sheet: 1 of: 1

FORM: PTO-	U.S. DEPARTMENT OF COMMERCE	Atty Docket No:	Serial No:
(REV: 7-80)	PATENT AND TRADEMARK OFFICE	94-0280.04	09/470,650
	3 RD	Applicant:	
INFOR	MATION DISCLOSURE STATEMENT BY APPLICANT	Thomas A. Figura et al.	
		Filing Date:	Group:
(37 CFR 1.98(b)	(use several sheets if necessary)	12/22/99	2813
•			

U.S. PATENT DOCUMENTS

Examiner		Document					
Initial		Number	Date	Name	Class	Subclass	
ALL	AA	6,117,764	09/12/00	Figura et al.	438	623	
IM	AB	5,950,092	09/07/99	Figura et al.	438	399	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	ΑI					T	
	ΑJ						
	AK						
	AL						
	AM						

FOREIGN PATENT DOCUMENTS

Examiner		Document					Trans	lation
Initial		Number	Date	Country	Class	Subclass	Yes	No
	AX							
	AY							

Initial		OTHER ART (including author, title, date, pertinent pages, etc.)
UK	AZ	Application Serial No. 09/470,651, entitled USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE, filed December 22, 1999; Thomas A. Figura, Kevin Donohoe, and Thomas Dunbar, inventors; attorney docket No. 94-0280.05; Preliminary Amendment filed December 22, 1999; Amendment After the Continued Prosecution Application and Response to the Office Action dated April 13, 2000 filed July 13, 2000; Response to the Office Action dated September 26, 2000 filed October 5, 2000; Amendment and Response to the Office Action Dated November 21, 2000 filed May 21, 2001.
MIL	ВА	Application Serial No. 09/471,460, entitled USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE, filed December 22, 1999; Thomas A. Figura, Kevin G. Donohoe and Thomas Dunbar, inventors; attorney docket No. 94-0280.03; Preliminary Amendment filed December 22, 1999; Amendment After the Continued Prosecution Application and Response to the Office Action dated June 6, 2000; Amendment and Response to the Office Action dated November 21, 2000, filed May 21, 2001.
Examiner:	24	Date Considered: 6/27/

EXAMINER:

Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.

	IN 2h MM OF THE TOWN		Sheet: 1 of: 1
FORM: PTO-14	49 U.S. DEPARTMENT OF COMMERCE	Atty Docket No:	Serial No:
(REV: 7-80)	PATENT AND TRADEMARK OFFICE	94-0280.04	09/470,650
		Applicant:	
INFORM	MATION DISCLOSURE STATEMENT BY APPLICANT	Thomas A. Figura et al.	
		Filing Date:	Group:
(37 CFR 1.98(b))	(use several sheets if necessary)	12/22/99	1765

U.S. PATENT DOCUMENTS

Examiner		Document					
Initial		Number	Date	Name	Class	Subclass	1
IME	AA	5,904,799	05/18/99	Donohoe	156	345	
Mc	AB	5,837,596	11/17/98	Figura et al.	438	446	
1410	AC	5,472,904	12/05/95	Figura et al.	437	67	
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ				i i		
	AK						
	AL						
	-AM	-					

FOREIGN PATENT DOCUMENTS

Examiner		Document					Trans	lation
Initial		Number	Date	Country	Class	Subclass	Yes	No
	AX							
	AY							

Initial			OTHER A	ART (including author, title, date, p	pertinent pages, etc.)	
	AZ					
	BA					
Examiner:		Lid		Date Considered:	8/2/1	
		-				

EXAMINER:

Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.

FORM: PTO-	1449		U.S. DEPARTM	IENT OF COMMERCE	Atty Docket No:	Serial No:			
(REV: 7-80)				TRADEMARK OFFICE	94-0280.04 Applicant:				
INE	ODMA'	TION DISCLOSI	IRE STATEME	ENT BY APPLICANT	Thomas A. Figura et al.		j		
INF	UKWA	HON DISCEOU			Filing Date:	Group:	o ==		
(37 CFR 1.98(b	9))		(use several	sheets if necessary)	12/22/99		<u>p</u>		
	<i>.,,</i>	_		U.S. PATENT DOCUMENTS	3	-	S. B.		
Examiner		Document	Data	Name	Class	Subclass			
Initial		Number	Date 10/13/98		257	759			
USIL	AA	5,821,621	09/08/98	Jeng Robles	427	577	- 18		
VIC	AB	5,804,259		Rhodes et al.	437	189	2 =		
MC	AC	5,496,773	03/05/96		437	195			
ins	AD	5,486,493	01/23/96	Jeng	437	195	-		
VAL	AE	5,476,817	12/19/95	Numata	430	313			
MC	AF	5,443,941	08/22/95	Bariya et al.	437	192			
MC	AG	5,422,310	06/06/95	lto	437	52	 		
UAR	AH	5,422,294	06/06/95	Noble, Jr.	156	643			
IAL	AI	5,382,316	01/17/95	Hills et al.	437	192			
UL	AJ	5,364,817	11/15/94	Lur et al.		52			
MC	AK	5,364,809	11/15/94	Kwon et al.	437	238			
ish	AL	5,354,715	10/11/94	Wang et al.	437				
UIL	AM	5,326,431	07/05/94	Kadomura	156	659.1			
in	AN	5,312,773	05/17/94	Nagashima	437	190			
Uh	AO	5,292,677	03/08/94	Dennison	437	52			
CAL	AP	5,286,675	02/15/94	Chen et al.	437	195			
IAL	AQ	5,284,787	02/08/94	Ahn	437	52			
iste	AR	5,232,509	08/03/93	Min et al.	118	723			
146	AS	5,185,282	02/09/93	Lee et al.	437	47			
	AT	5,162,248	11/10/92	Dennison et al.	437	52			
W.	AU	5,150,276	09/22/92	Gonzalez et al.	361	313			
, de	AV	5,110,712	05/05/92	Kessler et al.	430	312			
	AW	5,096,849	03/17/92	Beilstein, Jr. et al.	437	67			
ML	AX	5,084,413	01/28/92	Fujita et al.	437	189			
MC	AY	5,066,607	11/19/91	Banerjee	437	52			
ux			04/17/90	Bartha et al.	437	245			
LAIC	AZ	4,918,033	01/10/89	Malhi et al.	437	60			
Ale	BA	4,797,373	07/26/88	Numata et al.	427	255.6			
M	BB	4,759,958	07/26/88	Numata et ai.	427	255.0	<u> </u>		
Examiner		Document		FOREIGN PATENT DOCUME		C-halasa	Translation Yes No		
Initial		Number	Date	Country	Class	Subclass	163 140		
	BC					 	 		
	BD								
Initial			ОТ	HER ART (including author, title	, date, pertinent pages, etc.)				
1	Γ -	T T							
LAIC	BE Tetsuo Ono, Ryoji Hamasaki and Tatsumi Mizutani, "Mechanism for CF Polymer Film Deposition through Deep Sio Holes in Electron Cyclotron Resonance Plasma," Jpn. J. Appl. Phys. Vol. 35, pp. 2468-2471, Part 1, No. 4B, April 1996.								
LAK	BF		hrath, L. M., "Tei 37-4588, February	flon Polymer Mask For RIE of Cont y 1983.	tact Roles," IBM Technical Di	isclosure Bulletin,	, Vol. 25, No. 9, pp		
Examiner:				Date Consid	lered: T/. /				
Lammier.	4	AL	^		lered: T/r2(1				
		/	· · · · · · · · · · · · · · · · · · ·						
FYAMINFR.	1.	itial if rafararlas	onsidered wheth	ner or not citation is in conformanc	e with MPEP 609; Draw line	through citation i	t not in		

Initial if reference considered, whether or not citation is in conformance with MPEF 609, Draw line a conformance and not considered. Include copy of this form with next communication with applicant.